

SCIENTIFIC COMMITTEE

- V. Antoni - Consortio RFX, Padua (I)
- V. Belido-Gonzales - Gencoa, Liverpool (UK)
- N. Brenning - KTH, Stockholm (S)
- D. Depla - Univ. Gent (B)
- K. Hevesi - AGC Flat Glass Europe, Brussels (B)
- S. Lucas - Univ. Namur (B)
- W. Moëller - Dresden Univ. (D)
- F. Richter - TU Chemnitz (D)
- L. Roux - IBS, Peynier (F)
- S. Spencer - NCT, ME (USA)
- J. Vlcek - Plzen Univ. (CZ)

STEERING COMMITTEE

- T. Minea (*Chair*) - LPGP, Univ. Paris-Sud XI, Orsay (F)
- J. Bretagne (*Honorary member*) - LPGP, Univ. Paris-Sud XI, Orsay (F)
- M. Hecq (*Honorary member*) - UMH, Mons (B)
- G. Hirel - SFV, Paris (F)
- L. Le Brizoual - IMN, Univ. Nantes (F)
- C. Meunier - FEMTO-ST, Univ. de Franche-Comté, Besançon (F)
- J.M. Poirson - HEF Groupe, Andrézieux-Bouthéon (F)
- L. de Poucques - Institut Jean Lamour, Nancy (F)
- F. Sabary - CEA Le Ripault, Monts (F)
- R. Snyders - Materia Nova, UMONS, Mons (B)

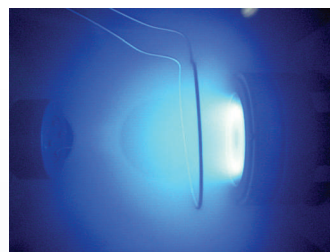
CONTACT, CONFERENCE SECRETARY

Société Française du Vide (SFV)

19 rue du Renard - 75004 Paris - France

sfv@vide.org

Phone: +33(0)1 53 01 90 30 - Fax: +33(0)1 42 78 63 20



1st Announcement

MIATEC 2010

**Tutorials,
Conferences,
Posters**

**Magnetron,
Ion processing
& Arc Technologies
European Conference**



**June 15-18, 2010
Metz, France
Congress Centre**

*In connection with SVTM
2010, International Exhibition
on Vacuum and
Surface Engineering*



www.vide.org/miatec2010.html



Organized by Société Française du Vide

19 rue du Renard - F-75004 PARIS

Phone: +33 (0)1 53 01 90 30 - Fax: +33 (0)1 42 78 63 20

Mail: sfv@vide.org - www.vide.org

SCOPE

The thin film deposition by **PVD** (Physical Vapor Deposition) is being drastically improved since the last decade by the rise of novel technologies such as **IPVD magnetrons** (Ionized Physical Vapor Deposition), **HPPMS** (High Power Pulsed Magnetron Sputtering), **IBAD** (Ion Beam Assisted Deposition), **non equilibrium low current arc discharges**, **very high pressure arc discharges**, **overheat reduction of arcs**, etc.

These technologies open the way for tailoring the film properties according to customer's requirements and for environmental friendly processes compared to classical wet deposition ones.

This Conference continues the 5th Edition - *Journées d'études "Nouvelles tendances en procédés Magnétron et arc pour le dépôt de couches minces"* (in French) in 2008 organised jointly by SFV (French Vacuum Society) and Belvac (Belgium Vacuum Society).

Taking into account the European dimension of the scientific and engineering community working in this area, it comes obvious that the next meeting – **MIATEC 2010** – has to be the echo of their research and the catalyst for efficient exchanges between the academic and industrial fields thus contributing to technological transfers.

MIATEC 2010 work program is planned to be parallel with two others important meetings organised by SFV, in the same place, namely

- **SVTM 2010**, *International exhibition for vacuum and surface engineering*
- **A3TS 2010**, *38th Congress of thermal treatment and surface engineering*



Tiberiu Minea
Chair of MIATEC 2010

TOPICS

- Sources
- Modelling
- Diagnostics
- Related Technologies
- Applications



GRANTS FOR STUDENTS

A limited number of grants will be available for PhD students. Candidates need to apply when submitting their abstract to the conference.

SHORT COURSES

The MIATEC 2010 Conference is preceded by one tutorial day (June 15) dedicated to main fields of interest « magnetrons », « arcs » and « ion assisted processing ».

LOCATION

Metz, a city open to:

- its European destiny, which it is building day after day with its immediate neighbours Luxembourg and Germany.
- its economic environment, encouraging the setting up of new activities, a source of new jobs for all and particularly the young
- the New Information and Communication Technologies, which it has made its speciality, developing since 1984 a Technopole entirely dedicated to those technologies, with 200 companies providing some 4,000 jobs.

IMPORTANT DATES

June 16-18, 2010	Conference
June 15, 2010	Tutorials
April 15, 2010	Acceptance notification
March 1 st , 2010	Deadline for abstract submission
January 2010	Call for papers
November 2009	1 st announcement